

### **Amendments to the Claims**

1. (Currently Amended) A method of monitoring operation of an automated tool comprising
  - positioning in close proximity to said automated tool at least one wireless sensor,
  - monitoring at least one condition of said automated tool by said sensor,
  - emitting signals containing sensor information in space to a microprocessor only if said at least one condition departs from a desired threshold value,
  - processing said sensor information in said microprocessor, and
  - in the event that the processor determines that said automated tool has departed from desired conditions of operation issuing a responsive signal.
2. (Currently Amended) The method of claim 1 including employing said method to monitor a said automated tool performing an operation on a workpiece.
3. (Original) The method of claim 2 including said at least one sensor being in a microelectromechanical system device.
4. (Original) The method of claim 3 including employing a plurality of said sensors in said method.
5. (Original) The method of claim 3 including measuring by said microelectromechanical system device at least one motion related characteristic of said automated tool.
6. (Original) The method of claim 2 including employing as said automated tool a progressive stamping press operating on a metal sheet workpiece.
7. (Original) The method of claim 3 including sensing by said microelectromechanical system device characteristics of said automated tool related to forces existing in the operation of said automated tool.
8. (Original) The method of claim 5 including monitoring said automatic tool properties by said microelectromechanical system device during at least a portion of a cycle of operation of said automated tool.

9. (Original) The method of claim 3 including monitoring at least one acceleration related characteristic of said operating automated tool.
10. (Original) The method of claim 1 including transmitting said sensor signals to said processor employing an RF carrier.
11. (Original) The method of claim 10 including transmitting said sensor information as digital information.
12. (Original) The method of claim 11 including employing in said microelectromechanical system device an inertial sensor.
13. (Canceled)
14. (Original) The method of claim 6 including employing said method to monitor misfeed.
15. (Original) The method of claim 1 including selecting said responsive signals from a group consisting of an automated tool shutdown, alarm signal and data delivery signal.
16. (Currently Amended) Apparatus for monitoring operation of an automated tool comprising  
an automated tool,  
at least one wireless sensor for monitoring a condition of said automated tool and emitting sensor signals through space only if a monitored condition departs from a desired threshold value,  
a microprocessor for receiving said sensor signals and determining if a departure from a desired characteristic exists and if so emitting a responsive signal.
17. (Original) The apparatus of claim 16 including  
said at least one wireless sensor being in a microelectromechanical system device.
18. (Original) The apparatus of claim 17 including  
said apparatus having a plurality of said sensors.
19. (Original) The apparatus of claim 16 including

said automated tool being a progressive stamping press for performing operations on a metal sheet workpiece.

20. (Original) The apparatus of claim 17 including  
    said microelectromechanical system device being structured to monitor force related characteristics.

21. (Currently Amended) The apparatus of claim 19 including  
    said microprocessor responsive signals being selected from thea group consisting of an automated tool shutdown signal, an alarm signal, and a data delivery signal.

22. (Currently Amended) The apparatus of claim 167 including  
    said microelectromechanical system device sensors being structured to monitor an acceleration related condition.